

IN THE SPECIFICATION:

Please amend the paragraph beginning at page 10, line 13, as follows:

The partition sheet 4 is provided at the joint part of the waveguide 2, and made of a low dielectric defect material, such as a PTFE sheet with a thickness of 3 mm. As shown in FIG. 2, the partition sheet 4 is held by an electrically conductive gland 23 and a faster fastener part on a mating surface of the waveguide 2. A shape inside the gland 23 needs to be the same as a sectional shape of the waveguide 2. In the instant embodiment, as shown in FIG. 2, a shape inside the gland 23 fits a shape in the waveguide 2. Since the partition sheet 4 should be held, the holder part preferably ~~is several millimeters that do not~~ has such a size of several millimeters that the holder part does not negatively affect propagations of the microwaves. In the instant embodiment, the gland 23 externally projects with a width of 3 mm, and has a dent with a length of about 3 mm to hold the partition sheet 4. The partition sheet 4 cools the dielectric 17, and prevents high-temperature coolant 33 from thermally negatively affecting the microwave oscillator 1 and an impedance matching unit (not shown).

Please amend the paragraph beginning at page 16, line 12, as follows:

The plasma processing apparatus 100A of the instant embodiment arranges comprises the heat conductive medium sheet 29 in the space in the coolant channel 11. The sheet 29 is heatproof and made of a material having high heat conductivity, such as

silicon powder and silicon oil. As shown in FIG. 8, the sheet 29 is arranged around the peripheral of the dielectric 17 so as not to close the slots 24 in the plate 16.